

Tuesday Morning, November 4, 2003

temperatures of up to 150°C (melting temperature of Bi is 220°C), where dewetting becomes important, even prior to melting.

10:40am **SS2-TuM8 Nucleation Kinetics during Homoepitaxial Growth of TiN(001) by Reactive Magnetron Sputtering**, *M.A. Wall¹, D.G. Cahill, I. Petrov*, University of Illinois at Urbana-Champaign; *D. Gall*, Rensselaer Polytechnic Institute; *J.E. Greene*, University of Illinois at Urbana-Champaign

Polycrystalline TiN is extensively used as a diffusion barrier in microelectronics, as a hard wear resistant coating on cutting tools, and as a corrosion and abrasion resistant layer on optical components. The performance of TiN in all these applications is dependant on the texture of the layer, which is in turn a function of the film growth parameters and nucleation kinetics. To gain an atomic-scale understanding of the processes which govern TiN nucleation, we grow epitaxial layers on TiN(001) via reactive magnetron sputtering in an ultra-high vacuum (UHV) system and employ in-situ scanning tunneling microscopy (STM) to investigate the dynamics. In addition, we perform density functional calculations in order to guide the interpretation of our experimental results. The characteristic island size $R_{\text{sub c}}$ necessary to nucleate a new layer on a growing island is measured as a function of growth temperature $T_{\text{sub s}}$ and nitrogen fraction $f_{\text{sub N2}}$ in an Ar/N₂ mixture. By applying nucleation rate theory to temperature dependant $R_{\text{sub c}}$ data obtained from layers grown with $f_{\text{sub N2}} = 1$, we extract a diffusion activation energy $E_{\text{sub s}} = 1.4 \pm 0.1$ eV for $T_{\text{sub s}} \leq 865$ °C where nucleation is diffusion limited. For $T_{\text{sub s}} \geq 910$ °C, nucleation becomes limited by the formation of unstable clusters, and we extract an adspecies formation energy $E_{\text{sub f}} = 1.4 \pm 0.2$ eV. When $f_{\text{sub N2}}$ is reduced from 1 to 0.1, $E_{\text{sub s}} = 1.1 \pm 0.2$ eV which results in a factor of two increase in $R_{\text{sub c}}$ at a given $T_{\text{sub s}}$. The activation energy we calculate for Ti diffusion on TiN(001) is 0.4 eV, significantly smaller than $E_{\text{sub s}}$ extracted from our experiment, indicating that Ti is not the dominant diffusing species. Based on calculated binding energies of TiN_x clusters, the dominant diffusing species is likely TiN_x, with $1 \leq x \leq 3$.

11:00am **SS2-TuM9 Pt Adsorption on Chiral SrTiO₃ Surfaces**, *A. Asthagiri, D.S. Sholl*, Carnegie Mellon University

The existence of intrinsically chiral surfaces provides many opportunities related to the catalytic chemistry and separation of chiral molecules. A key difficulty in realizing the potential of this approach has been the production of surfaces with reasonable surface area. We describe results that underpin efforts to epitaxially deposit ultra-thin films of metal on metal oxide substrates. The success of these efforts requires careful control of the film morphology of the underlying substrate and knowledge of the growth modes of metal on these surfaces. To this end, we have performed extensive plane wave Density Functional Theory (DFT) calculations to describe the bonding of Pt on a variety of SrTiO₃ surfaces. These calculations include both terminations of all three low Miller index surfaces, (100), (110), and (111), and two representative stepped surfaces, (620) and (622). Our results show that epitaxial growth of Pt on the substrates can be expected, and that step flow growth should be feasible for the stepped substrates. Our results provide quantitative insight into the experimental observations made by our collaborators for these systems, including the existence of inversion domains for Pt films on SrTiO₃(111). We will discuss the implications of our calculations for the practical growth of chiral metal films on SrTiO₃ substrates.

11:20am **SS2-TuM10 High-Temperature Low Energy Electron Microscopy Studies of Spiral Dislocation Dynamics on TiN(111) Terraces**, *S. Kodambaka, S.V. Khare, W. Swiech, K. Ohmori, I. Petrov, J.E. Greene*, University of Illinois at Urbana-Champaign

We have grown epitaxial TiN(111) layers by reactive evaporation onto Al₂O₃(0002) substrates and used in situ high-temperature low-energy electron microscopy to study surface morphological evolution on large (> 4 μm) atomically-smooth TiN(111) terraces during annealing at temperatures $T_{\text{sub a}}$ in the range 1500 and 1750 K ($T_{\text{sub a}} = 0.47-0.55T_{\text{sub m}}$, where $T_{\text{sub m}}$ is the melting point in K). At each annealing temperature, we observe rotation of screw dislocation segments lying in the surface slip plane around the immobilized segment of the dislocation lying out of the slip plane resulting in a spiral with steps oriented along . Step heights are proportional to the number of revolutions in the slip plane. We find that the total length of the dislocation line increases with annealing time as the spirals undergo a shape-preserving

anti-clockwise motion with a constant angular velocity. From the temperature-dependent angular velocity measurements, we determine an activation barrier of 5.0 ± 0.2 eV, with a prefactor of $10^{\pm 0.5}$ s⁻¹, for spiral rotation. Studies of this process, a single-ended Frank-Read source, provide insight into understanding dislocation multiplication mechanisms occurring in highly refractory, technologically important transition-metal nitride layers.

11:40am **SS2-TuM11 Conversion from Nanowire to Epilayer: Epitaxial Growth of Bi on Si(114)-2x1**, *S. Cho, J.M. Seo*, Chonbuk National University, Korea

The Bismuth (Bi) adsorption on the reconstructed Si(114)-2x1 has been studied using STM under UHV. Among 1-D features of Si(114)-2x1, such as Tetramer, Dimer and Restatom rows parallel to [-110] direction, Bi atoms preferentially adsorbed on the Tetramer rows and formed 1-D wires whose separation is 1.6 nm. The periodic structure in the Bi wire along [-110] has been converted to 3a (a=0.38 nm) from 2a of clean Si(114). The Bi wire of the second layer adsorbs between the Bi wires of the first layer, and shifts by 1.5a along the row. The Bi wires of subsequent layers also adsorb between the previously formed Bi wires in the same fashion. Such epitaxial growth continues unless the defects like substrate vacancies interfere. The packing unit is a Bi-dimer and the hexagonal packing has been confirmed by the hexagonal pattern of the facet near the ledge. It has been concluded that the reasons for 2-D epitaxial growth of Bi on Si(114) are the followings; the first, the existence of preferential adsorption site on Si(114), and the second, the adjustable lattice-matching between the Bi-dimer row and the substrate along as well as perpendicular to the wire.

¹ Morton S. Traum Award Finalist

Author Index

Bold page numbers indicate presenter

— A —

Asthagiri, A.: SS2-TuM9, **2**

— B —

Bartelt, M.C.: SS2-TuM5, **1**

Bartelt, N.C.: SS2-TuM4, **1**

— C —

Cahill, D.G.: SS2-TuM8, **2**

Cho, S.: SS2-TuM11, **2**

— D —

Dougherty, D.B.: SS2-TuM1, **1**

— E —

Einstein, T.L.: SS2-TuM3, **1**

Evans, J.W.: SS2-TuM5, **1**

— G —

Gall, D.: SS2-TuM8, **2**

Giessel, T.: SS2-TuM4, **1**

Greene, J.E.: SS2-TuM10, **2**; SS2-TuM8, **2**

— H —

Hwang, R.Q.: SS2-TuM4, **1**

— K —

Khare, S.V.: SS2-TuM10, **2**

Kodambaka, S.: SS2-TuM10, **2**

Kolodziej, J.: SS2-TuM6, **1**

— L —

Li, M.: SS2-TuM5, **1**

Ling, W.L.: SS2-TuM4, **1**

— M —

Madey, T.E.: SS2-TuM6, **1**

McCarty, K.F.: SS2-TuM4, **1**

— O —

Ohmori, K.: SS2-TuM10, **2**

— P —

Petrov, I.: SS2-TuM10, **2**; SS2-TuM8, **2**

— R —

Reutt-Robey, J.E.: SS2-TuM1, **1**

— S —

Sadowski, J.T.: SS2-TuM7, **1**

Seo, J.M.: SS2-TuM11, **2**

Sholl, D.S.: SS2-TuM9, **2**

Swiech, W.: SS2-TuM10, **2**

Szalma, F.: SS2-TuM3, **1**

— T —

Thayer, G.E.: SS2-TuM7, **1**

Thürmer, K.: SS2-TuM4, **1**

Tromp, R.M.: SS2-TuM7, **1**

— W —

Wall, M.A.: SS2-TuM8, **2**

Wang, H.: SS2-TuM6, **1**

Wu, Q.: SS2-TuM6, **1**